Quick Start Guide: XeF₂ Etcher

This short document is for helping users remember how to operate the tool. It does not replace the SOP nor training.

1. Check to see that XeF₂ valve is closed

2. Activate the tool on NEMO

3. Check to see that the tool is in ‘Standby’ mode

4. Fill in relevant information to the log sheet

5. Click ‘Remove Wafer’, unscrew black knob, and wait until step is complete

In case of emergency, call DPS: 213-740-4321

Written by Eugene Yoon, May 2023
6. Open chamber, load sample(s), close chamber, then tighten black knob
7. Click ‘Purge’ and wait until step is complete
8. Open the XeF<sub>2</sub> valve

9. Click ‘Pulse Etch’ and wait until step is complete
10. Close the XeF<sub>2</sub> valve

11. Click ‘Remove Wafer’ and wait until step is complete
12. Unscrew the black knob and remove your sample(s)
13. If you have more samples, load them and repeat the procedure from step 6
14. If you are finished etching, close the chamber and tighten the black knob, and click ‘Standby’
15. Wait 2 minutes
16. Fill in the ‘End Status’ on the log sheet and add any comments in ‘Notes’ (if you have any)
17. Deactivate tool on NEMO